



Nano
Fabrication
Center

Odem Evaporator

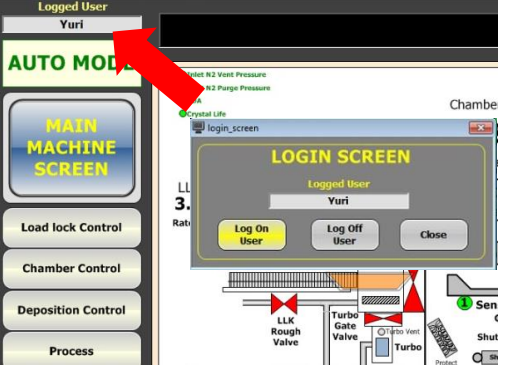
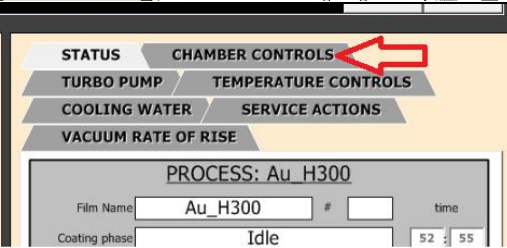




Standard Operating Procedure


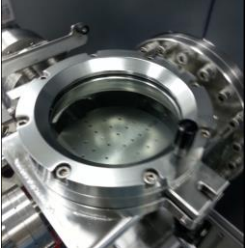
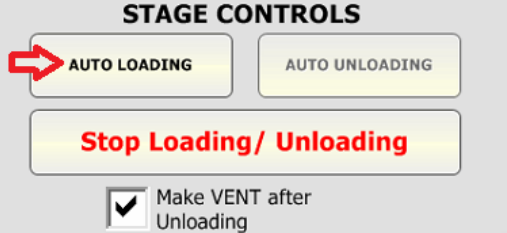
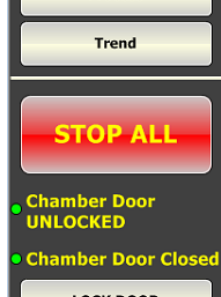
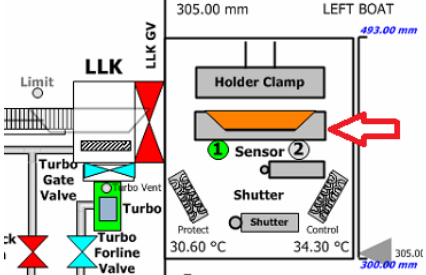




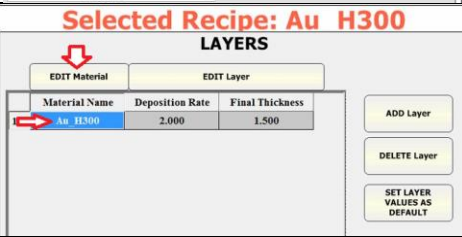
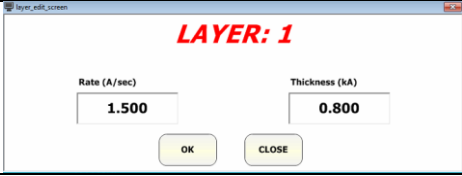

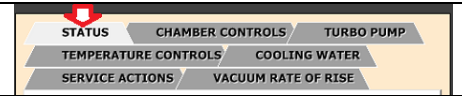


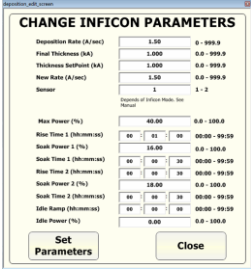
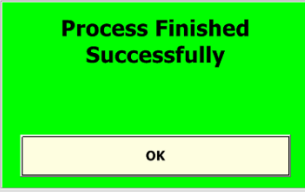
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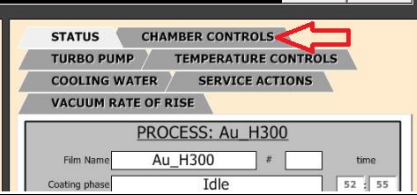
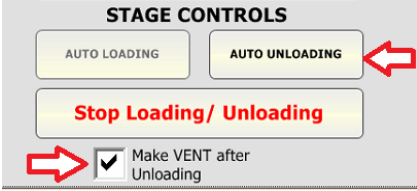
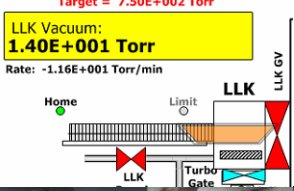

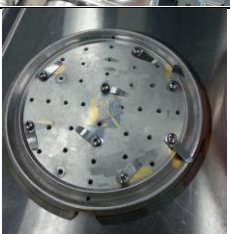

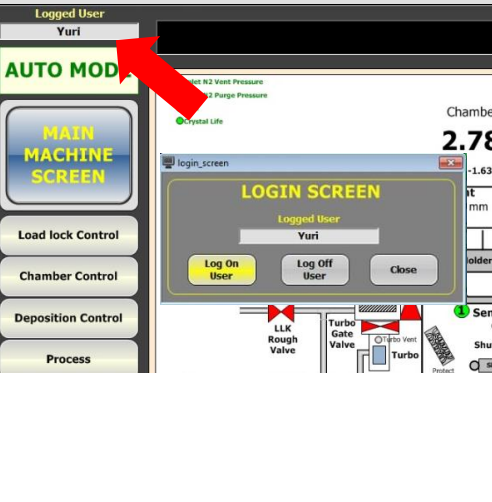
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Standard Operation

<p>1</p>	<p>Log in to system by pressing the logged user on the upper left corner.</p>	
<p>2</p>	<p>On the upper right side at Main screen set tab to chamber controls.</p>	
<p>3</p>	<p>Press the start Loadlock vent button (red) wait till pressure in it reaches 7.5 e2.</p>	
<p>4</p>	<p>Open the loadlock chamber door.</p>	
<p>5</p>	<p>Take sample holder out from the Load lock using the special tool.</p>	
<p>6</p>	<p>Attach your samples to the sample holder.</p>	

7	Place sample holder in the load lock and <u>make sure it seats tight in its place by trying to move it in its place by your hand.</u>	
8	Close the load lock door.	
9	If you need plasma of O2 or Ar go to step 31	
10	Press the Auto Loading button	
11	If you wish to stop any action of the instrument press the STOP ALL button.	
12	Wait till the transfer procedure has finished and the sample was placed in the main chamber.	
13	Go to process section By pressing the Process button on the left side of the main screen.	

14	Choose the recipe you desire at the recipe list.	
15	Choose the film you want to edit and then press edit Layer (the deposition parameters will appear on the right side of the screen).	
16	Set the rate and thickness you desire and press OK.	
17	If you wish to edit another layer go to step 15	
18	When all parameters are set to your satisfaction press the RUN RECIPE at the bottom of the screen The screen will transfer to main screen and will start the process.	
19	Press the status tab on the upper right and view that the process is functioning properly.	
20	If you wish to change the process parameters press the deposition control button and then the edit deposition controller parameters	
21	Change the parameters you desire	
22	Press set parameters if you wish parameters to set. Press the close button if you finished editing the layer at run	
23	When process complete a message will appear Process complete.	

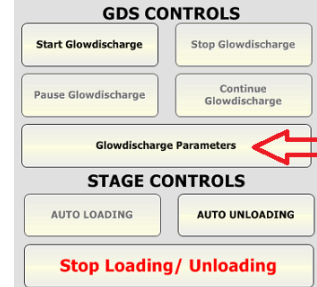
24	In order to take out the sample holder press the chamber control tab	
25	Press auto unloading button Activate the make vent after unloading if you wish the instrument to vent the load lock automatically	
26	When chamber reached atmosphere (7.5 e-2) Open the load lock door	
27	Take out the sample holder using the special tool.	
28	Remove the samples from the sample holder	
29	Place the sample holder back in the load lock and pump the chamber by pressing the start loadlock vacuum .	
30	Log out	

Plasma Ashing

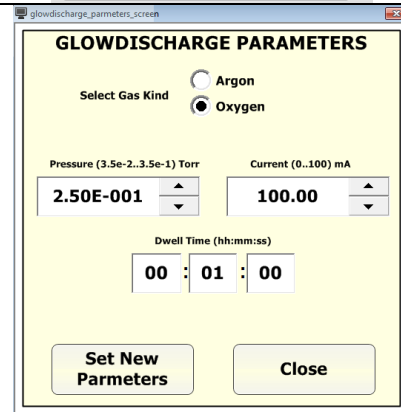
31 Pump the Load lock chamber by pressing the **start Load Lock Vacuum** button on the chamber controls tab



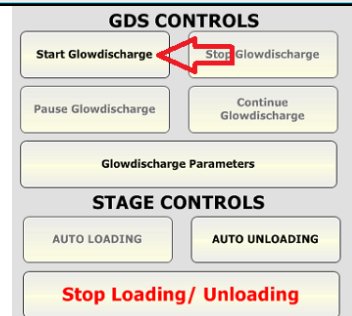
32 If you wish to do O2 or Ar glow discharge than check the **glow discharge parameters** button at the control tab on the right side of the screen at GDS control.



33 A new window will open **Set the parameters according to your needs** depending on the gas, power, pressure and time. After updating press the set new parameters button



35 Press starts glow discharge at the GDS control ones the chamber have reached 5E-5 Torr Vacuum



36 To view the plasma processes **press the Load Lock process**.
The main screen will change and will show the Load lock control and values.
Ones the process has finished the load lock will pump itself.



Go to step 10 to continue the Evaporation

process.

